

EDITORIAL

IMPLEMENTING JM³ ACRONYMS

In my July 2007 editorial I wrote about acronyms and the need to provide an acronym reference for the fields of micro/nanolithography, MEMS, and MOEMS. As I stated there, it is relatively easy to create a new acronym, and some authors do this rather than take the time to look up the original one. There is also the satisfaction of creating one's own acronym. As a result, new acronyms proliferate, despite confusion and inconsistency. Therefore, it is desirable to provide a reference list of acronyms dedicated to the JM³ areas. Starting with this issue of JM³, a list of acronyms in the fields of micro/nanolithography, MEMS, and MOEMS will be published. We plan to publish the list annually in print, and it will also be posted online. There are many ways to use the list. Following are my suggestions.

Authors: When you prepare a manuscript, look for existing acronyms on the official list and use them. Before submitting the manuscript, please double-check the list. When you use or create a new acronym not listed, gather them on a separate page entitled "List of Acronyms" so that we can consider updating the list. If you have an issue with any of the terms, write to me or the associate edi-

tor with your reasons. We will continue to refine the list. But remember, anytime you use an acronym, whether it's on the list or not, always define it in the manuscript at the first usage.

Editors: Please review the acronyms used in the manuscript and ask the authors to use existing ones instead of creating new ones, unless they have strong reasons to do so. Please review and approve the list of new acronyms that the authors include in their manuscript.

Readers: Give me your opinion on the acronyms on the list. Send me any missed acronyms that you think should be added to the list.

Happy reading!



Burn J. Lin
Editor-in-Chief